

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Henry F. Erk et al. Art Unit 1765
Serial No. 10/665,982
Filed September 18, 2003
Confirmation No. 5374
For PROCESS FOR ETCHING SILICON WAFERS
Examiner Eric B. Chen

August 28, 2006

LETTER TO THE PATENT AND TRADEMARK OFFICE

TO THE COMMISSIONER FOR PATENTS,

SIR:

In response to the Office action mailed May 30, 2006,
please consider the following remarks.

Remarks begin on page 2 of this Letter.